ocket No. 0756-2419

#6/A 5/193

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

| In re Patent Application of |  | )   | Art Unit: 1765  |
|-----------------------------|--|-----|---|
| Naoaki YAMAGUCHI et al.     |  | ( ر | Examiner: A. Alanko   |
| Serial No. 10/035,441       |  | )   | Confirmation No. 4492   |
| Filed: January              | 4, 2002                                      | )   | CERTIFICATE OF MAILING  |
| For: OPTICA                 | or: OPTICAL PROCESSING APPARATUS AND OPTICAL | )   | <ul> <li>I hereby certify that this correspondence is being deposited with The United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents,</li> </ul> |
| APPARA                      |  | )   |   |
| PROCE                       | SSING METHOD )                               |     | P.O. Box 1450, Alexandrja, VA 22313-1450, on <u>5.21.03</u>   |

## **AMENDMENT**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

RECEIVED

MAY 2 7 7003

Sir:

**GROUP 1700** 

In response to the Official Action dated February 21, 2003, please amend the above-identified application as follows:

## IN THE SPECIFICATION:

At p. 1, before the first line of the specification, please insert the following:

AI

--The present application is a Divisional of Serial No. 09/547,716, filed April 11, 2000, now U.S. Patent No. 6,336,969; which itself is a Divisional of Serial No. 08/451,648, filed May 26, 1995, now U.S. Patent No. 6,059,873.--

## IN THE CLAIMS:

1. (Amended) An optical processing method comprising the steps of: preparing a semiconductor film over a substrate;

irradiating a laser light onto said semiconductor film to crystallize said semiconductor film, and